

# NUFAB Facility



**MICRO/NANO FABRICATION FACILITY** 

NUFAB is a central micro/nano fabrication facility at Northwestern University. It provides the whole range of nanofabrication equipment and technical expertise to Northwestern as well as other academic and industrial researchers. We support research in all areas of science, engineering, medicine, and interdisciplinary fields

A video tour of our facility is available here. If you would like physical tour or have any questions, send us an email at nufab@northwestern.edu



# ELECTRON BEAM LITHOGRAPHY

### **Raith Voyager 100**

- <10 nm structures</li>
- cm scale exposure
- High speed pattern generator
- 50 kV





#### **Contact Information**

**NUANCE** Center - **NUFAB Technological Institute - F-Wing** nufab.northwestern.edu





Abraham Harris NUANCE Center

www.nuance.northwestern.edu

# Northwestern University **Micro/Nano Fabrication Facility**

# CHARACTERIZATION



Professor, Materials Science & Engineering Founding Director



Dr. Serkan Butun Equipment Manage



Dr. Anil Dhote Equipment Manager

– N. Moldovan, Alcorix Co







# PHOTOLITHOGRAPHY



NUFAB's Photolithography Bay is configured for both mask and maskless lithography processes, including single micron scale optical lithography.

**Below**:

A 3 pJ/bit free space optical interlink platform for self-powered sensing & opto-spintronic RF-to-optical transduction - Mohseni Group, Northwestern





Above: Ambipolar inverters based on cofacial vertical organic electrochemical transistor pairs for biosignal amplification – Rivnay Group, Northwestern

 Mask Aligners Suss MABA6, Suss MJB4

 Laser Writer Heidelberg MLA150, uPG 501

> Convection Ovens Blue M DCC-146-C-ST350

> > Microscope Nikon LV150

Spinner Hood

 Automatic Develop Hood Osiris UNIXX

 Ultraviolet Flood Exposure System Inpro Technologies F300S

 Ultrasonic & Megasonic Cleaners

VacuumOven (YES)

Dr. Ying Jia Equipment Manager















# Northwestern Exploring Inner Space

## **DEPOSITION & ETCH**



NUFAB's Deposition Bay is suitable for a wide variety of deposition techniques, including both PVD anf CVD methods.

- Automatic Acid Etcher
- Annealing Tube Furnace Lindberg/Blue M
- Plasma Enhanced Chemical Vapor Deposition STS LpX CVD
- AJA E-Beam Evaporator
- Thermal Evaporator Denton Vacuum Explorer 14
- Parylene Coater SCS Labcoter2 Parylene Deposition System
- Sputters AJA Orion Sputter I & II
- Deep Reactive Ion Etcher (DRIE) STS LpX Pegasus
- Reactive Ion Etcher (RIE) Samco RIE-10NR
- Xenon Difluoride Etcher Xactix
- Rapid Thermal Processor (RTP) AW-610
- P/N Doping Furnaces
- Tystar Low Pressure CVD
- Critical Point Dryer Tousimis Automegasamdri – 915B, Series C

## 23 years of excellence